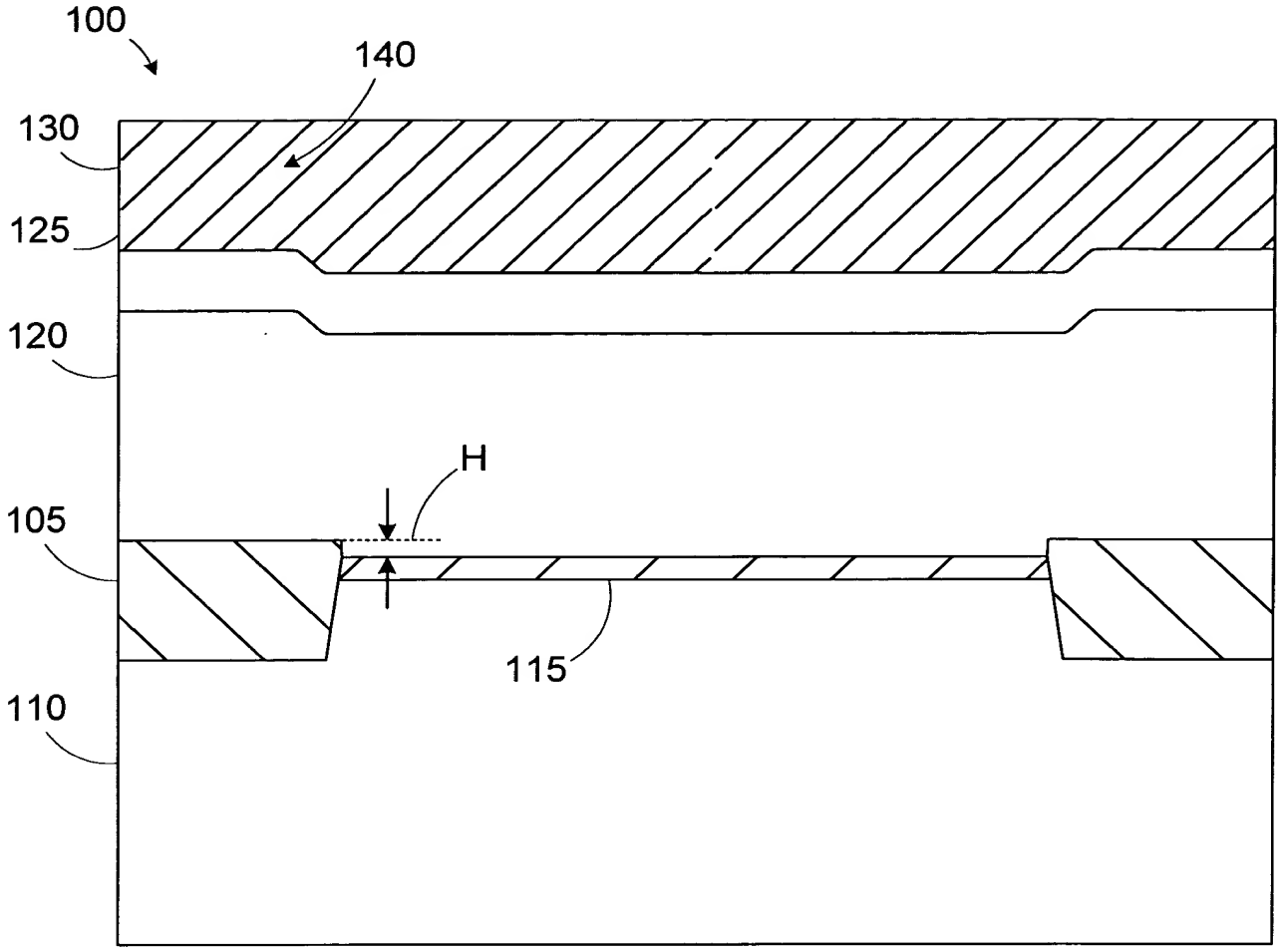

Figure 1A
(Prior Art)

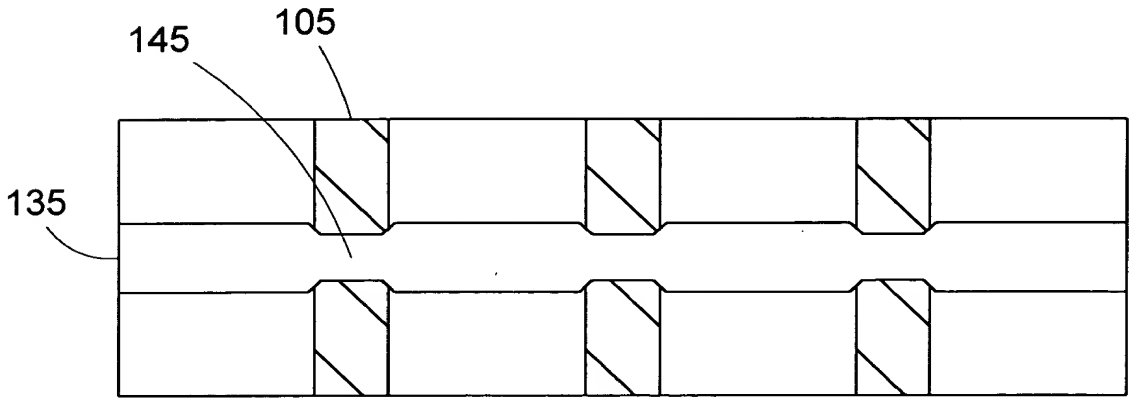

Figure 1B
(Prior Art)

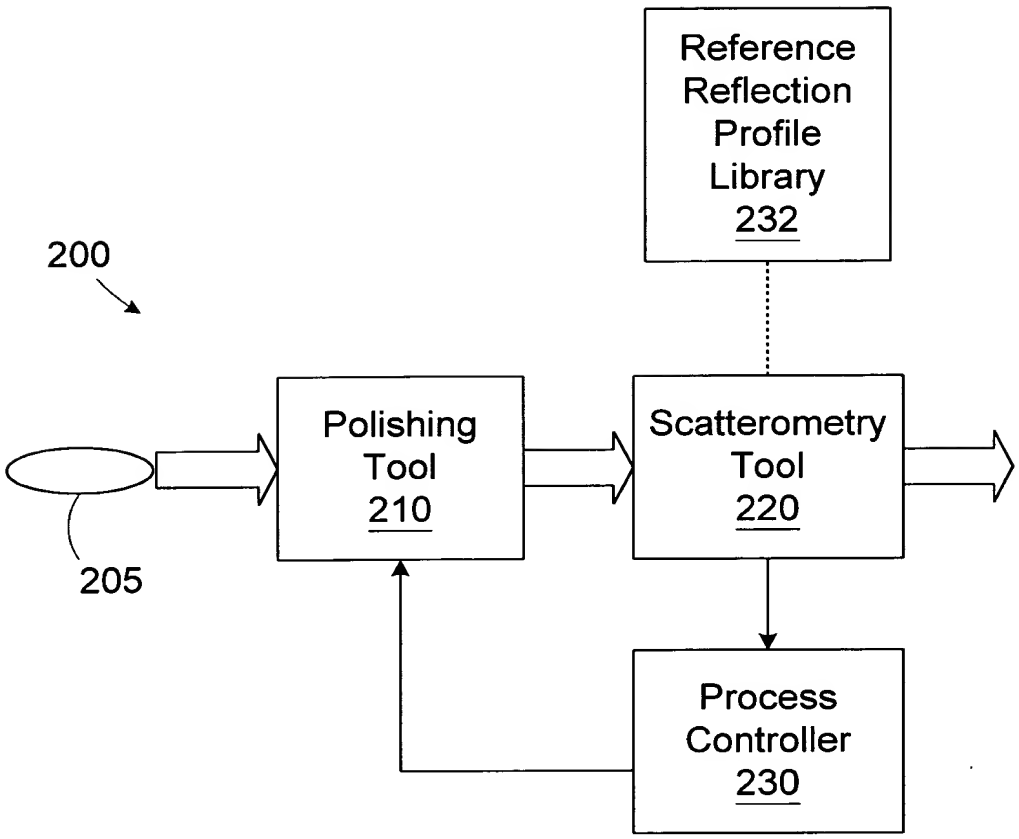
Reference
Reflection
Profile
Library
232
200
Polishing
Tool
210
Scatterometry
Tool
220
205
Process
Controller
230

Figure 2

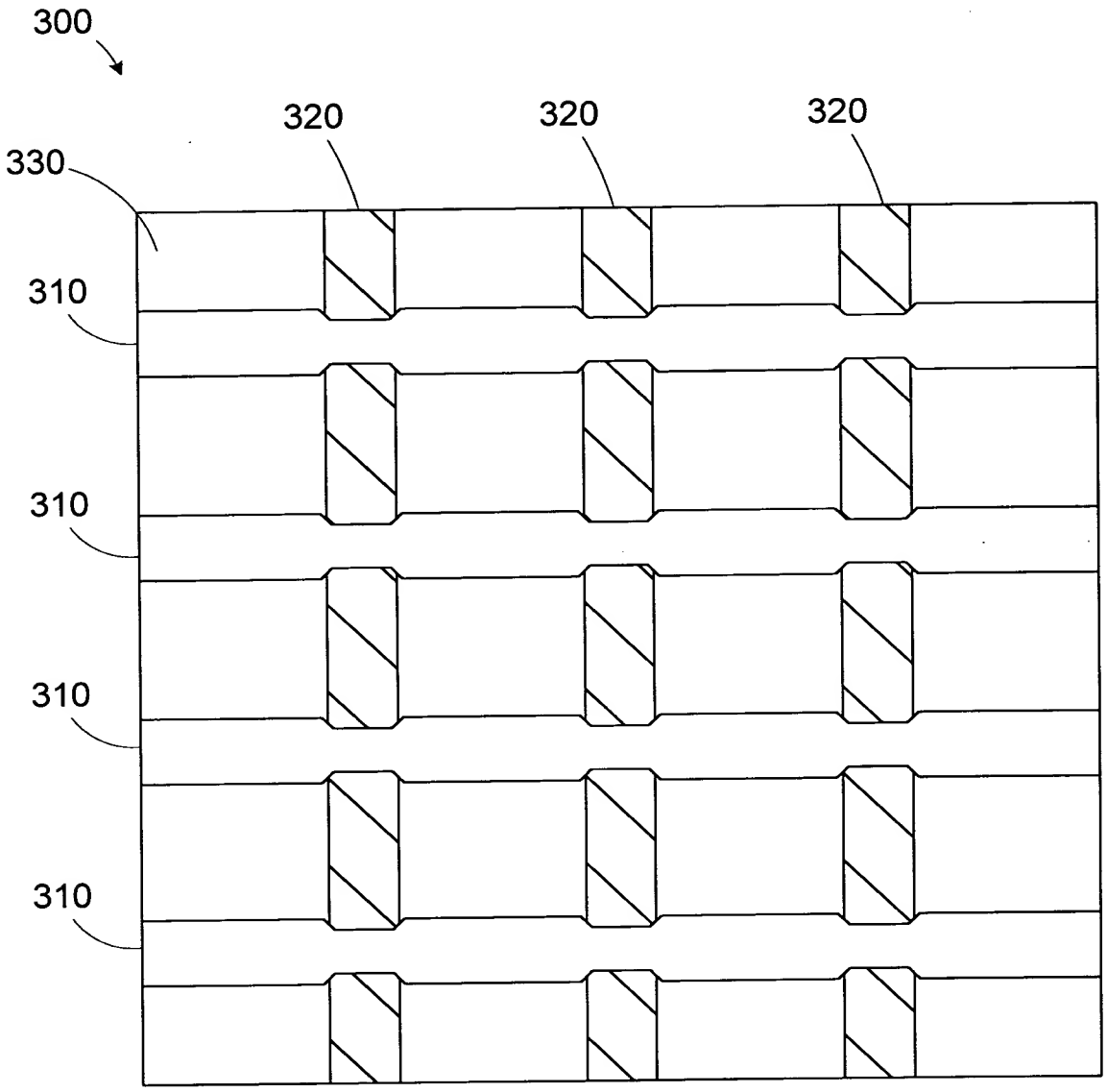

Figure 3

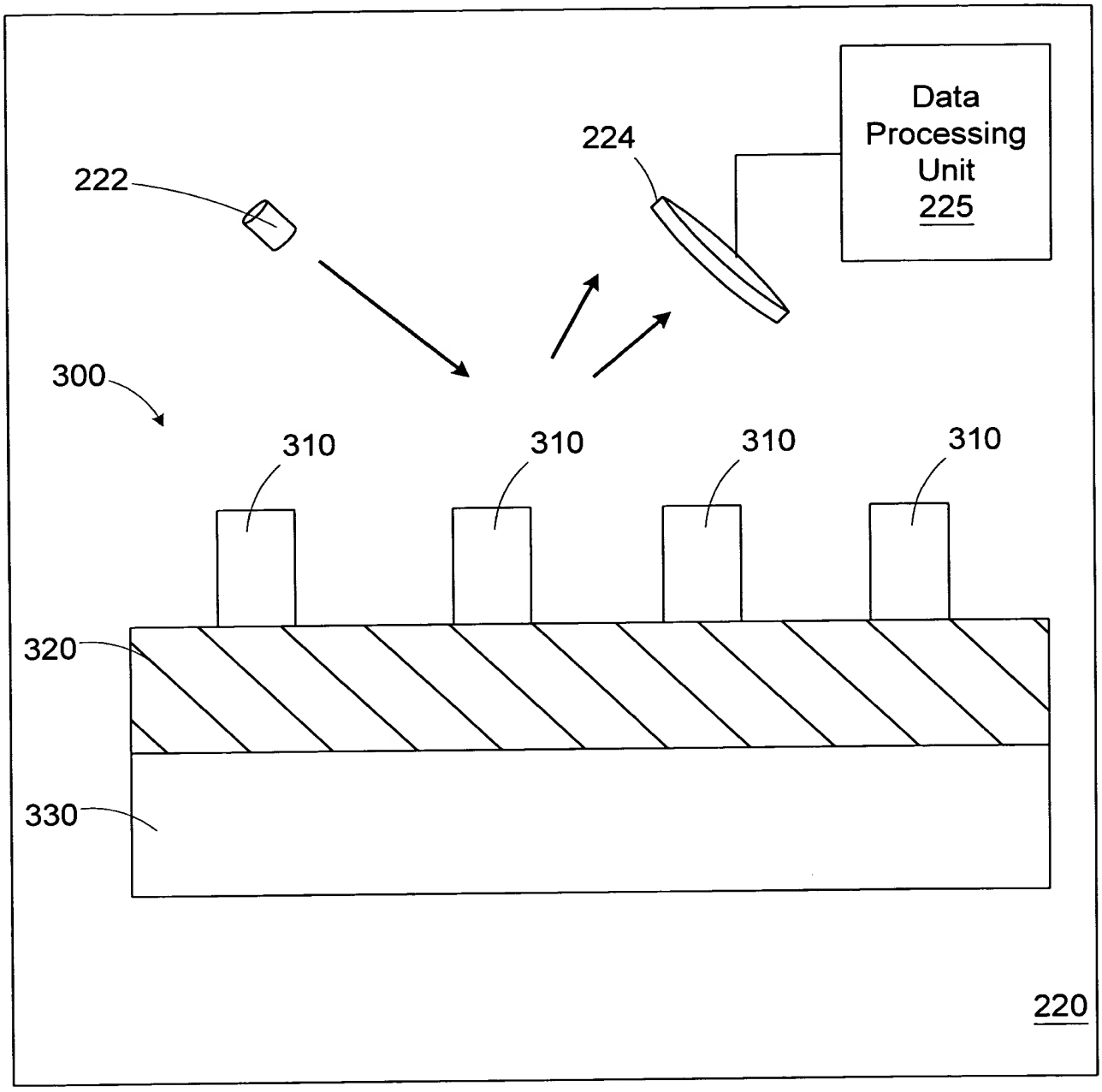
Data Processing Unit 225
224
222
300
310
310
310
310
320
330
220

Figure 4

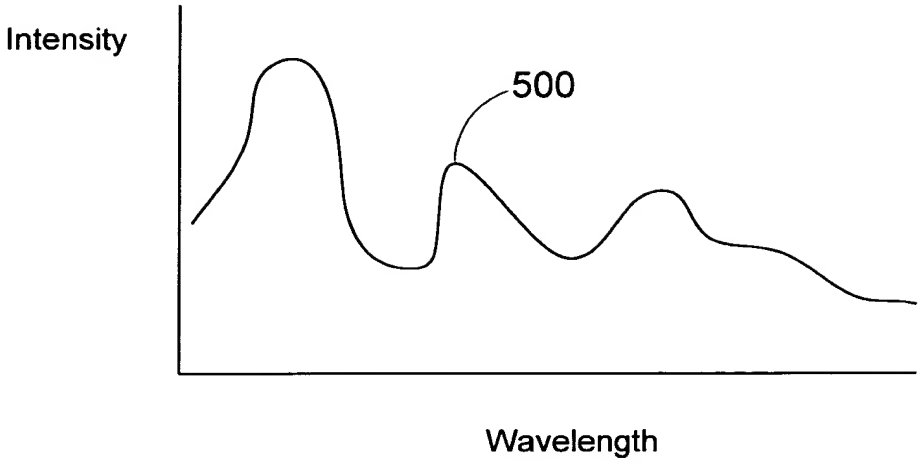

Figure 5A

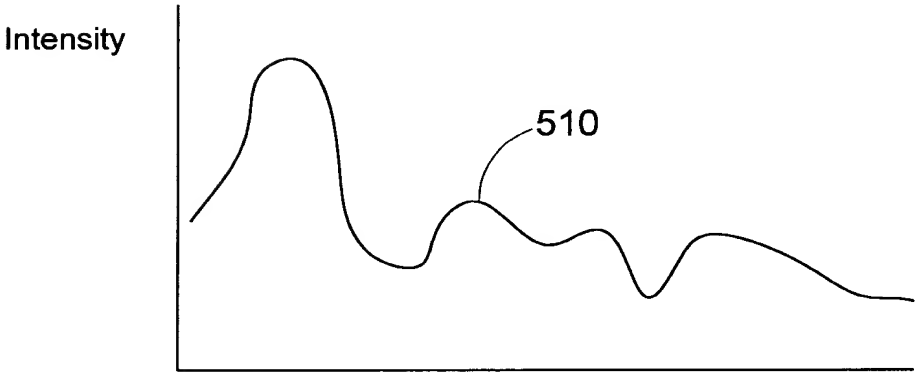

Figure 5B

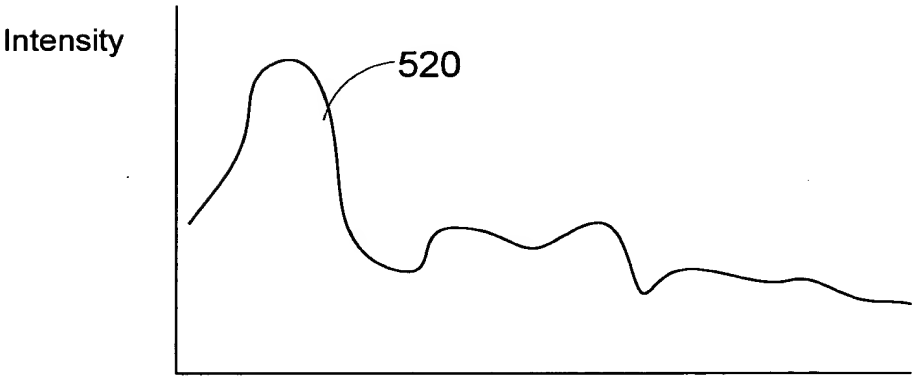

Figure 5C

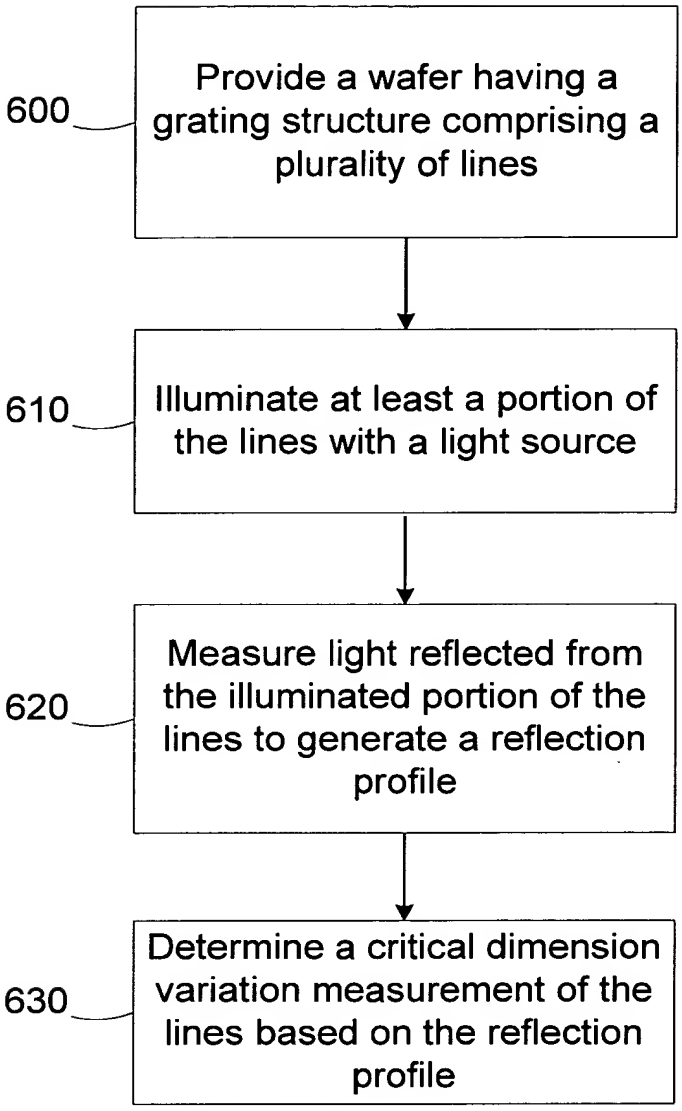
600
Provide a wafer having a grating structure comprising a plurality of lines
610
Illuminate at least a portion of the lines with a light source
620
Measure light reflected from the illuminated portion of the lines to generate a reflection profile
630
Determine a critical dimension variation measurement of the lines based on the reflection profile

Figure 6